

# Characteristic Transconductance of P-Type and N-Type Deeply Depleted Graphene-Insulator-Semiconductor Junction Photodetectors

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# Outline

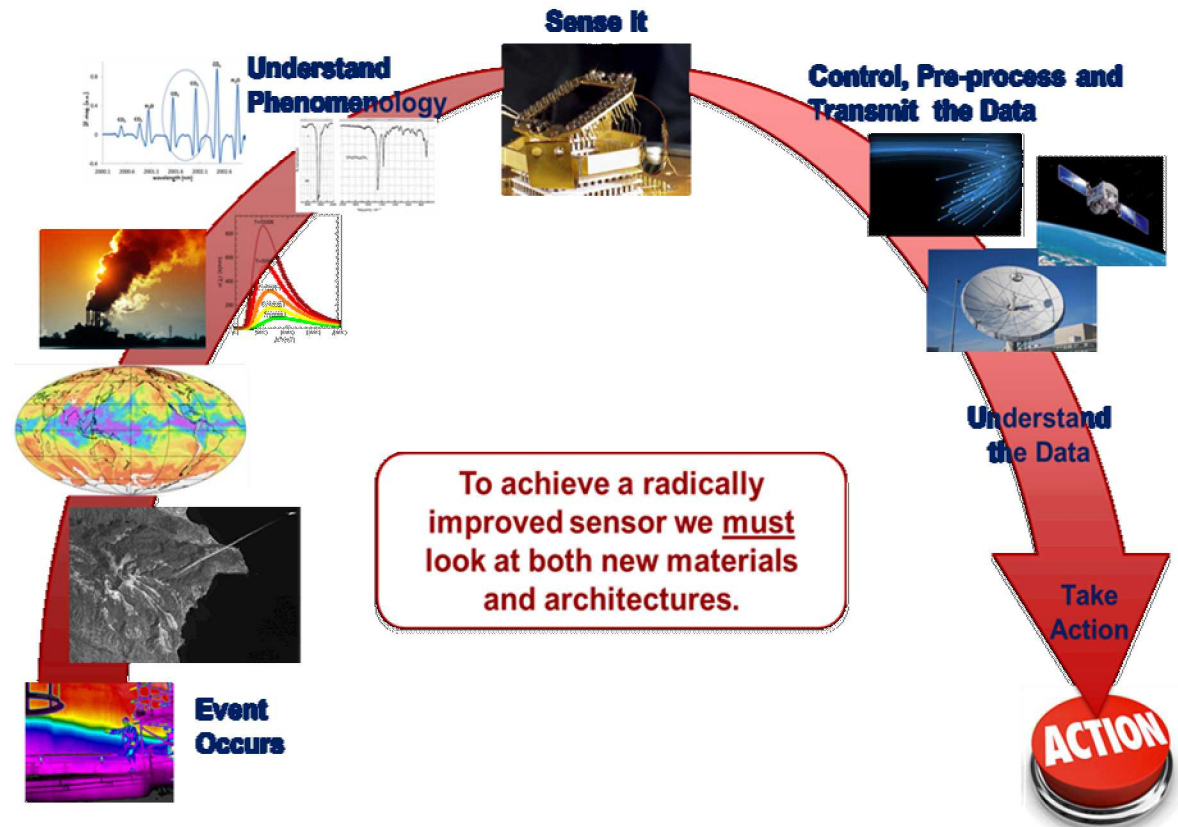
- Motivation
- Background of the D<sup>2</sup>GOS Junction Detector
  - Operating Principles
  - First generation device performance
- Improving the D<sup>2</sup>GOS Detector
  - Reducing interface states
  - Well Lifetime measurements
- N-type and P-type D<sup>2</sup>GOS Visible Detectors
  - Semiconductor doping
  - Graphene doping
  - Experimental Demonstration
- Demonstration of D<sup>2</sup>GOS in the near Infrared

# Smart Sensors Technology Grand Challenge

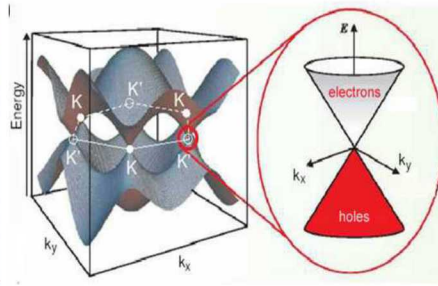
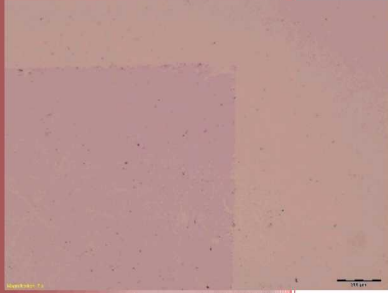
**Goal:** Develop the foundation for a new infrared detector that will lead to an order of magnitude improvement in noise, higher resolution, and real-time spectrally tunable pixels.

## Thrusts:

- Tune the Resonance
  - Control the resonance of nanoantennas
- Tune the Detector
  - Control absorption into materials
- Improve Performance



## Novel 2D Material



- Ultra-High Mobility
- Broadband Optical Absorption
- Tunable Electronic/Optical Properties
- Scalable

- Many demonstrations of sensing across EM spectrum (UV to IR)

## Poor

Electrically thin

absorption

Short combination with

## Solution:

Don't Absorb into the Graphene

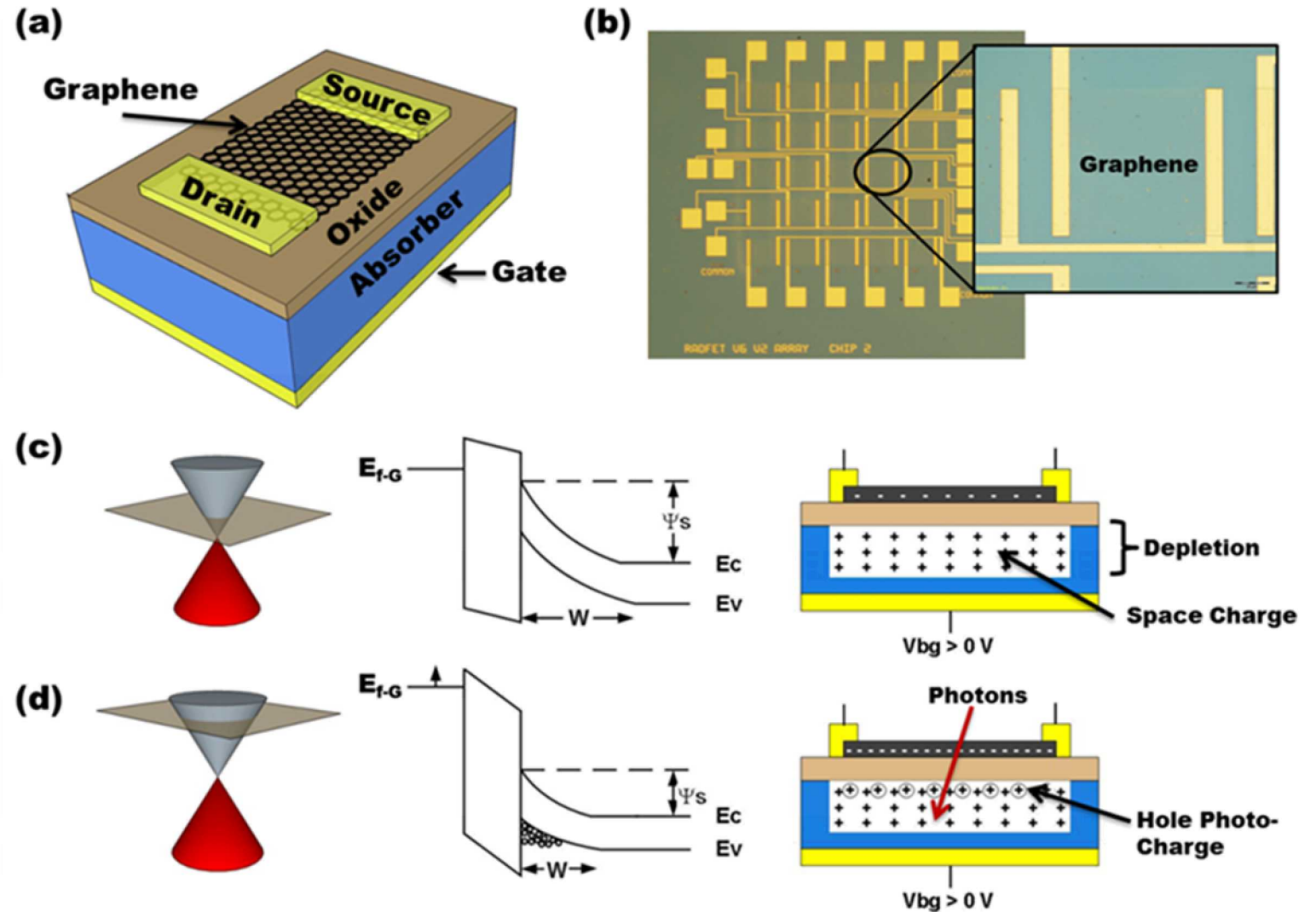
Use graphene to sense photo-generated generating in a **good** absorber.

Contact doping

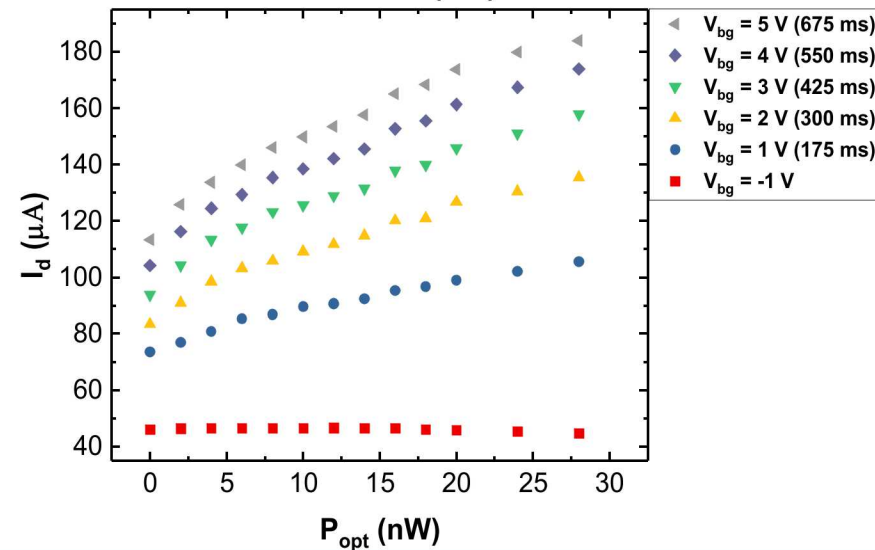
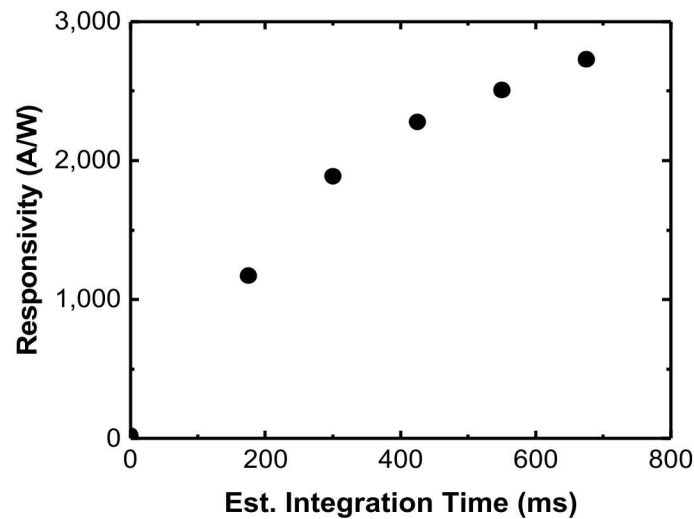
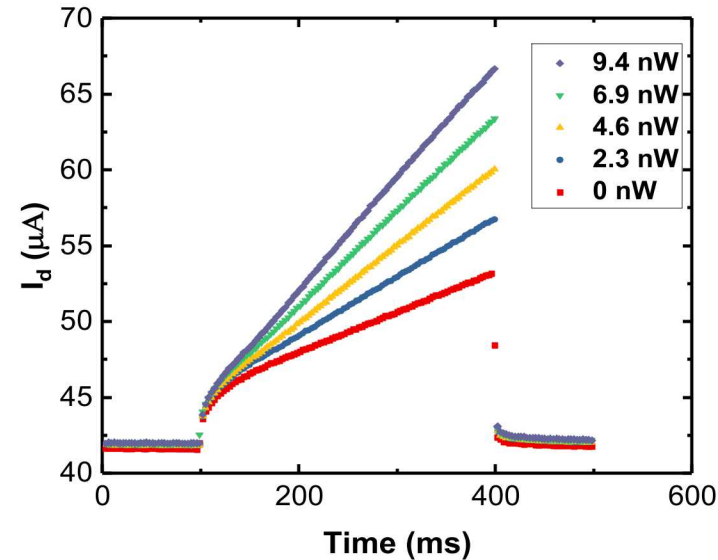
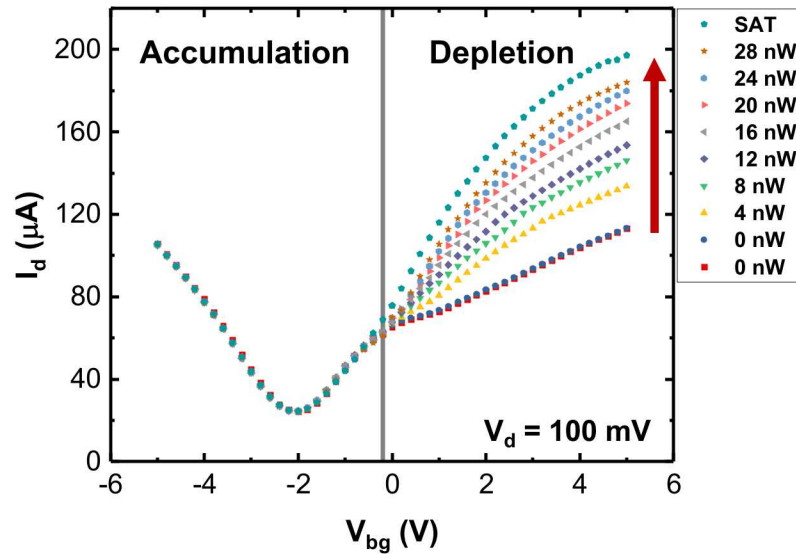


# What is the Deeply Depleted GIS Junction and how does it Work?

1. Absorber-Oxide-Graphene Junction.
2. Low doped absorber is depleted with an applied back gate voltage.
3. Incoming light creates photo-generated charge in absorber.
4. Built in electric field separates electron-hole pairs.
5. Charge accumulates at semiconductor/Oxide interface.
6. Graphene FET senses accumulated charge



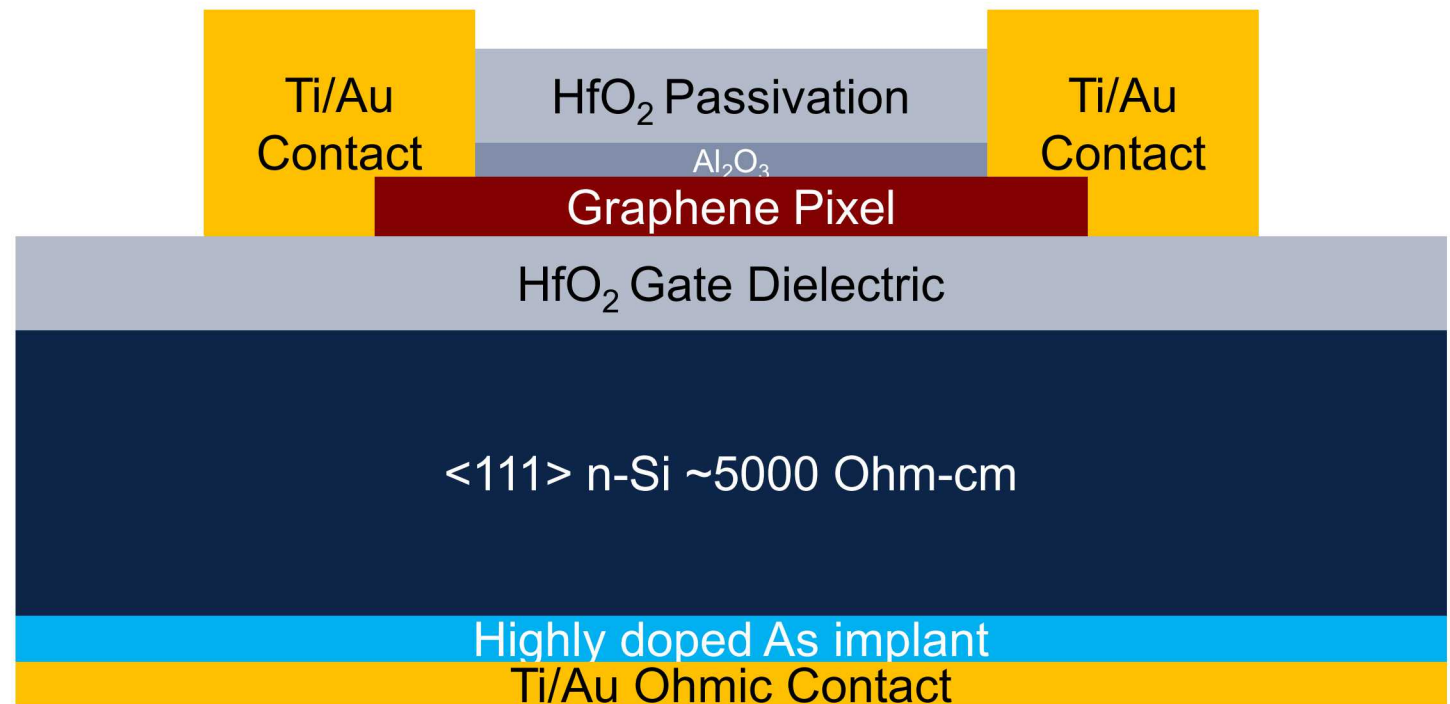
# First Generation Devices



- Fabricated on low doped n-doped silicon for absorption in the visible regime.
- Graphene was slightly n-doped, close to intrinsic.
- Demonstrated nW sensitivity.
- High Responsivity
  - 2500 A/W

# First Generation Device Architecture

- **Devices functioned but nowhere near optimized.**
- **Problems**
  - Poor interface between Si and HfO<sub>2</sub>.
    - 111 surface forms bad interface.
    - Potential well fills up quickly (~8 sec)
  - Graphene mobility ~1200 cm<sup>2</sup>/s.
    - Near low end of CVD graphene quality
- **Only one of several possible configurations.**

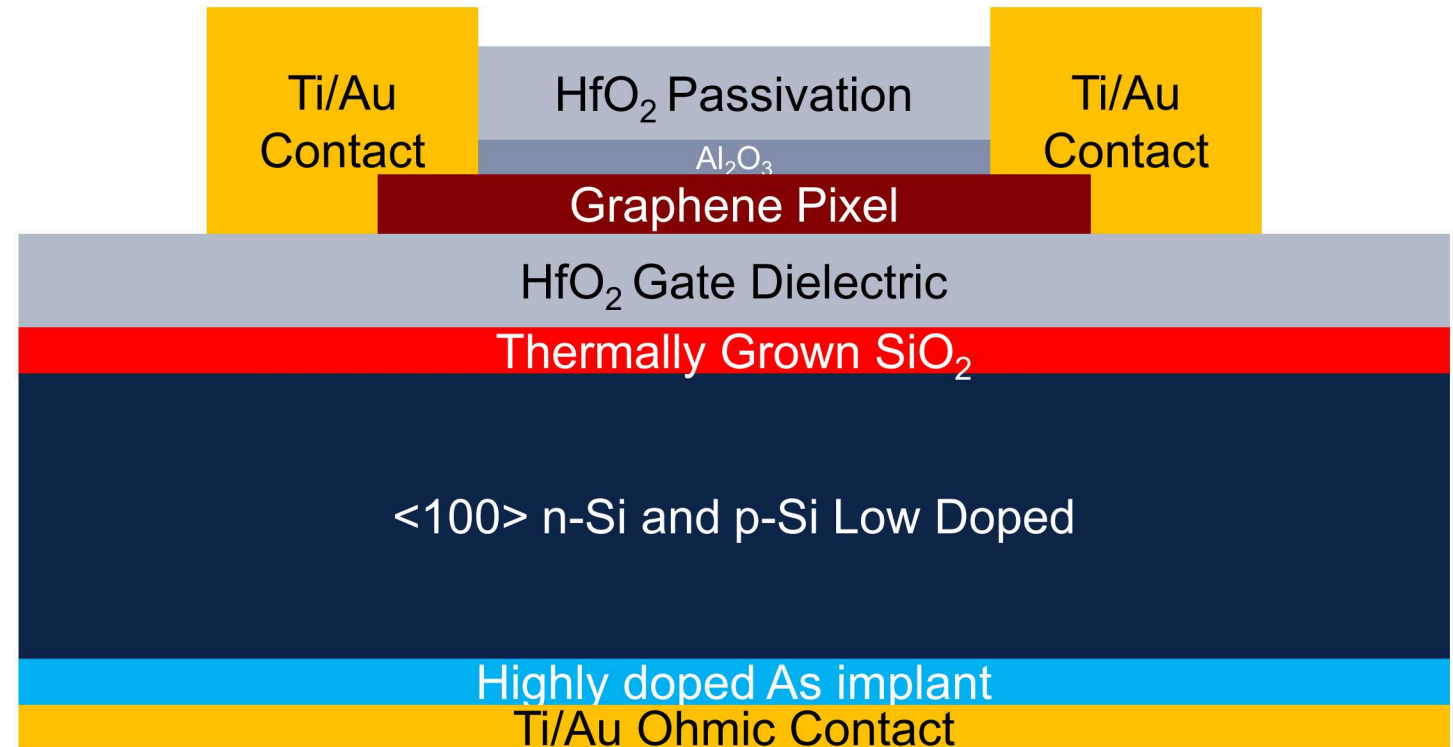


# Next Generation Device Architecture

- **Start designing for optimization**

- ✓ Lower Interface States
- ✓ Different Absorbers
- ✓ Graphene Doping
- Increased graphene mobility

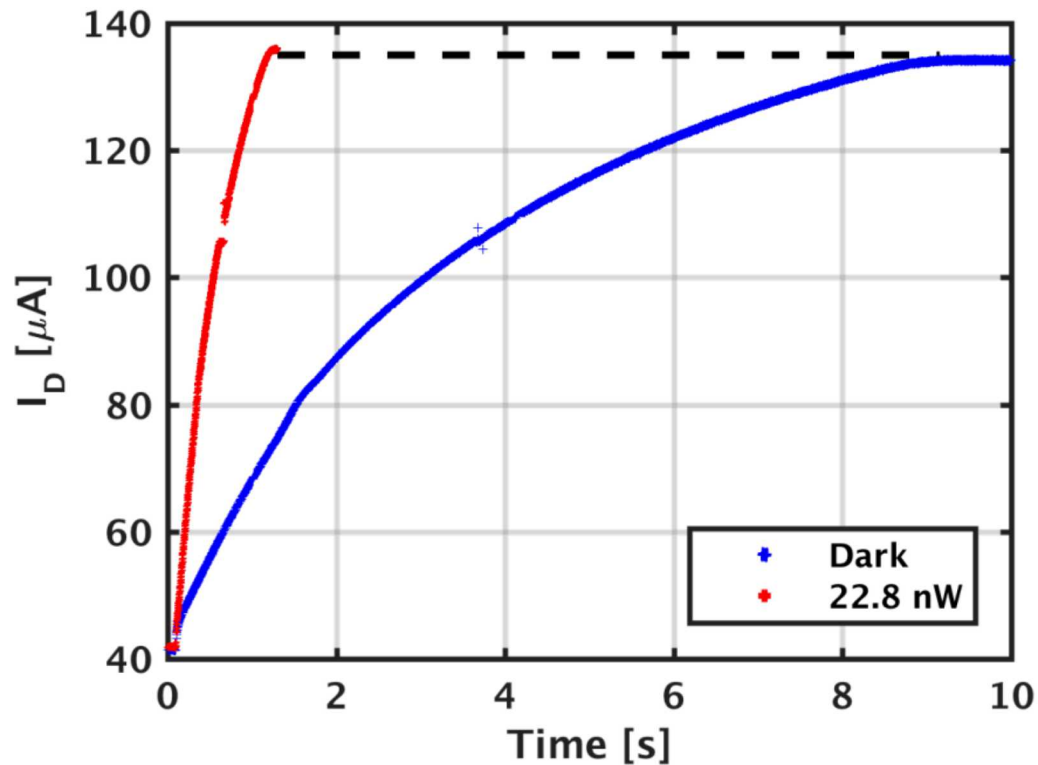
- **Explore the possible configurations of substrate doping and graphene doping.**



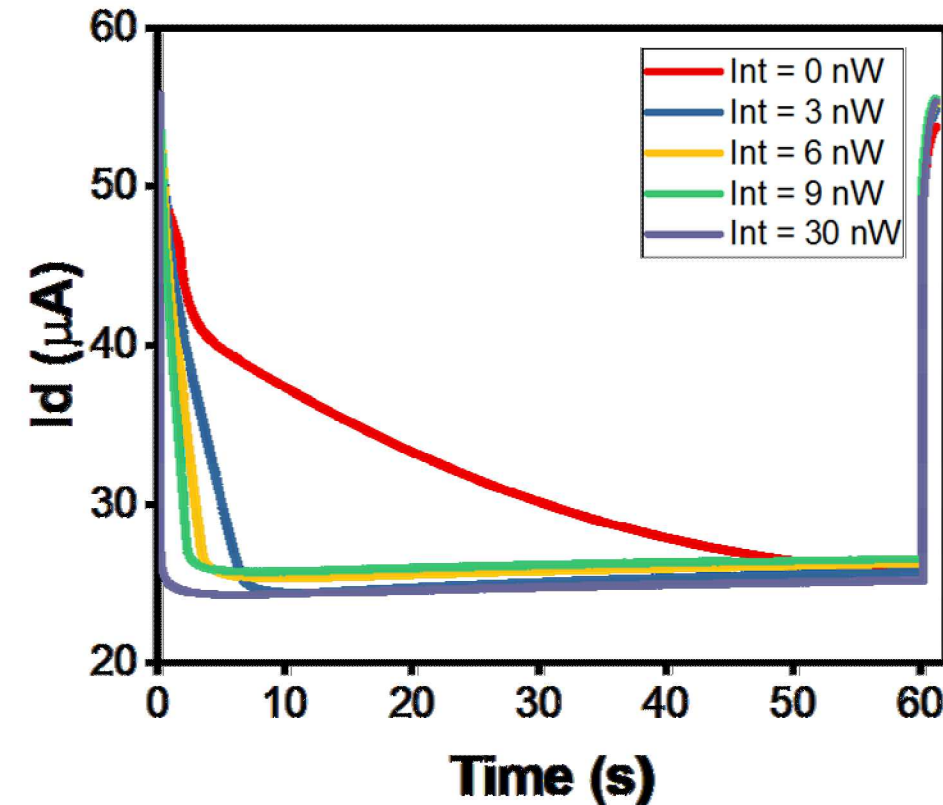


# High Quality Interface Effect on Well Filling

## Poor Quality Interface

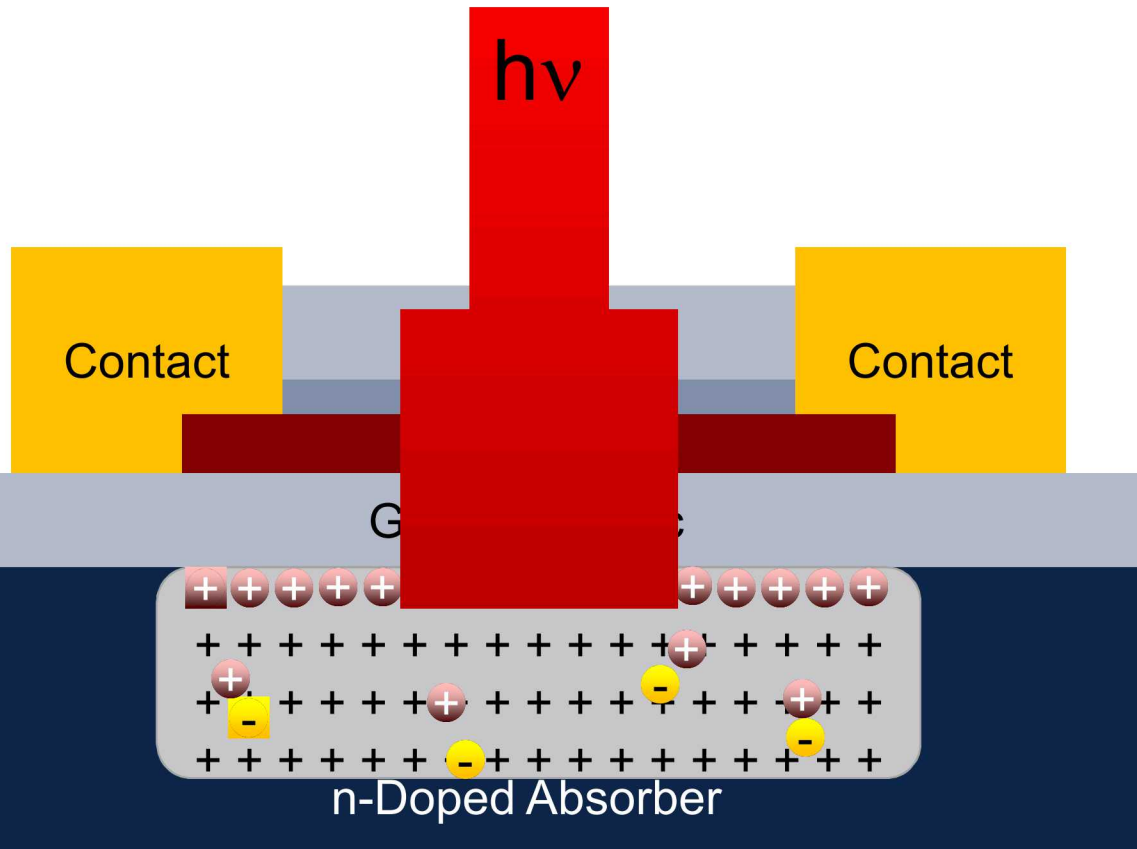


## High Quality Interface

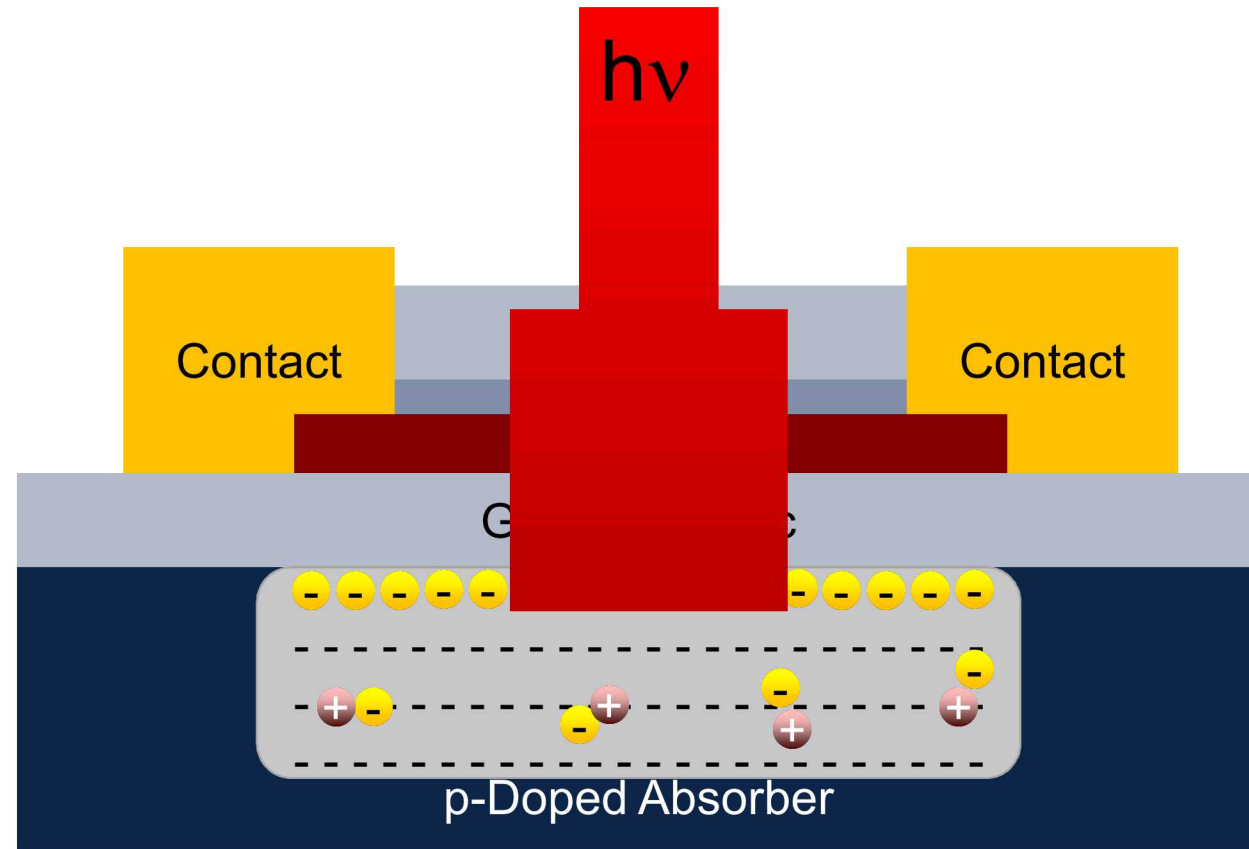


**Note:** This device architecture allows for direct visualization and read-out of the charge collecting at the absorber/oxide interface.

# P-Type and N-Type D<sup>2</sup>GOS



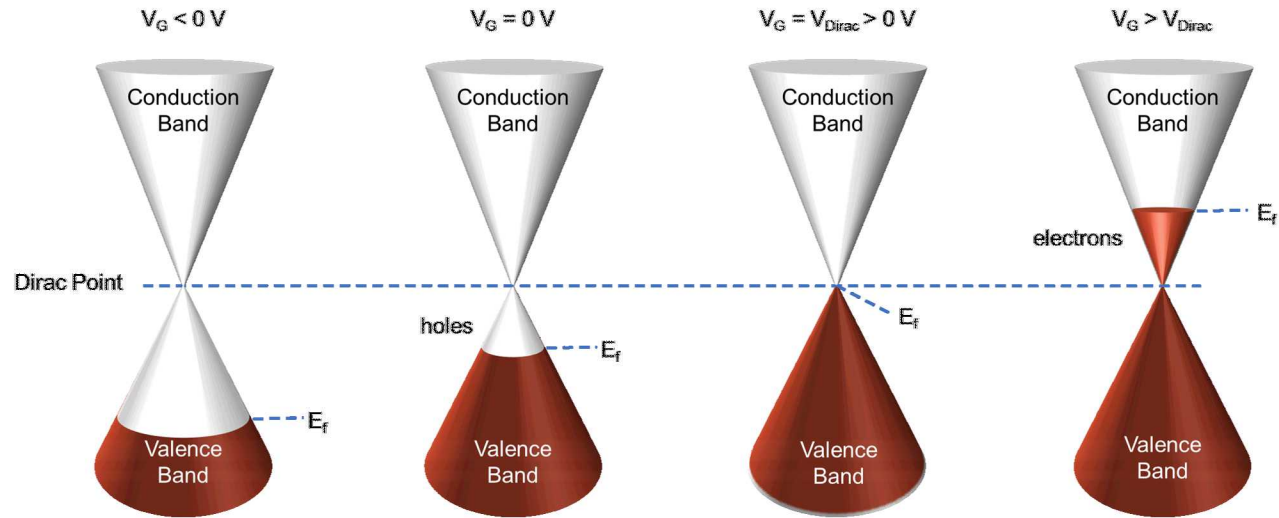
$$V_{bg} > V_{fb}$$



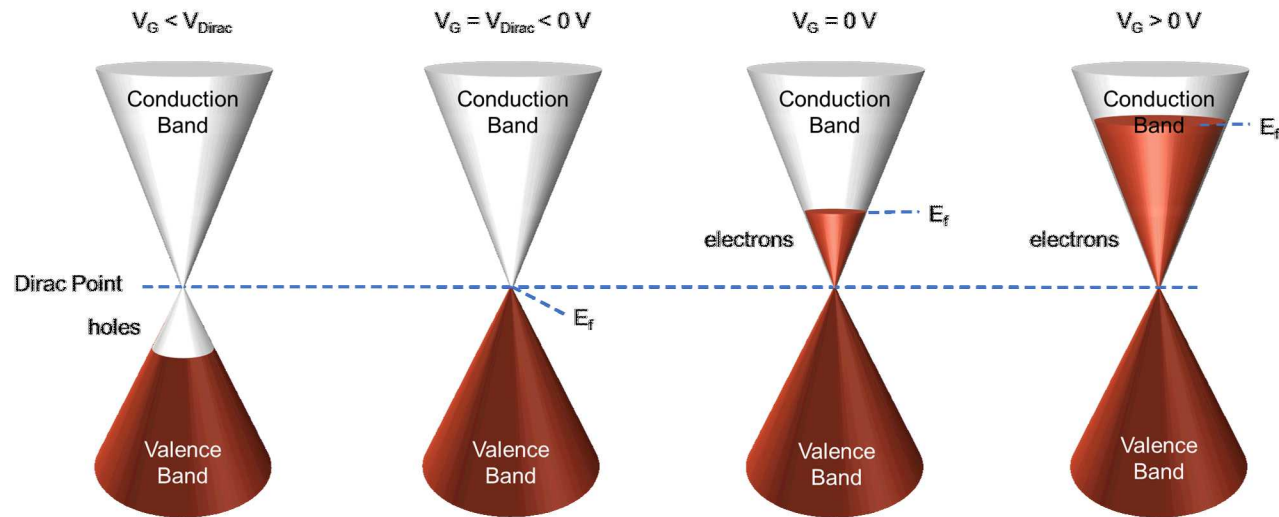
$$V_{bg} < V_{fb}$$

# Graphene is Doped

p-doped Graphene

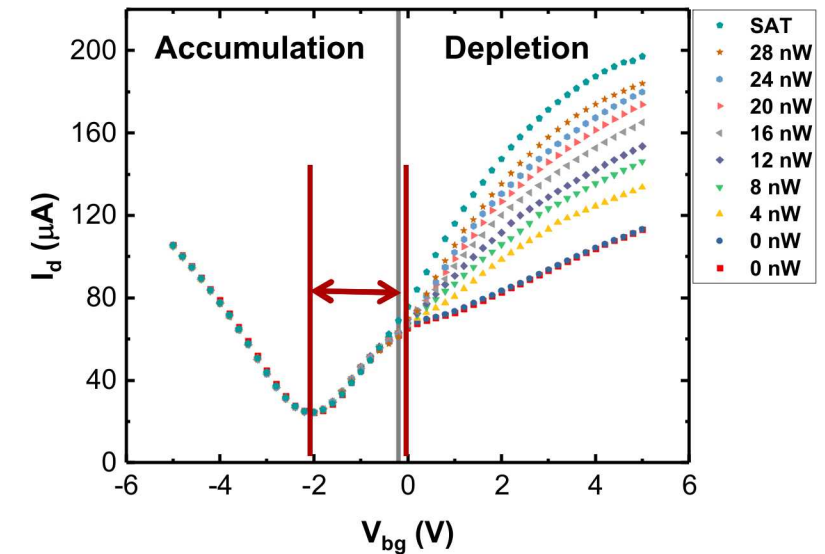


n-doped Graphene



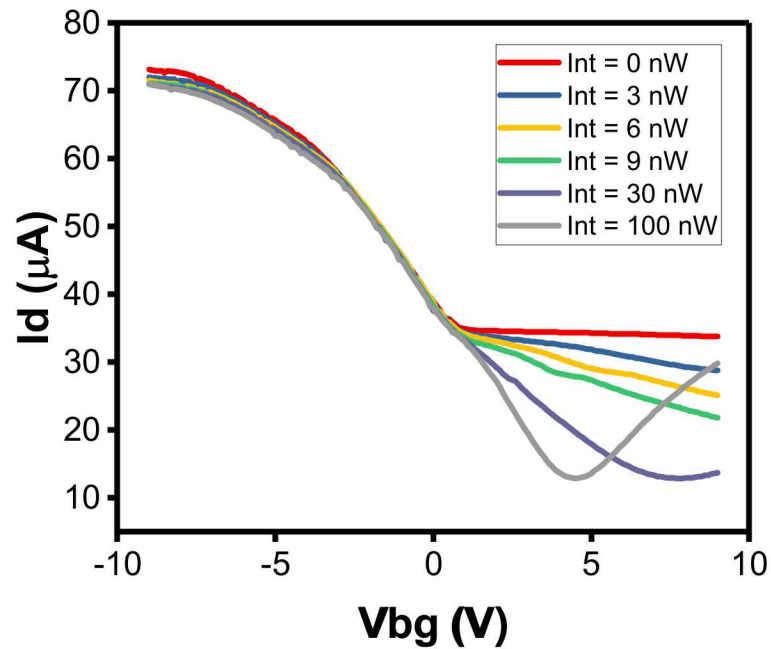
First Generation Devices were n-doped Graphene on n-Si.

This provided very predictable, easy to understand  $I_d(V_{bg})$  curves.

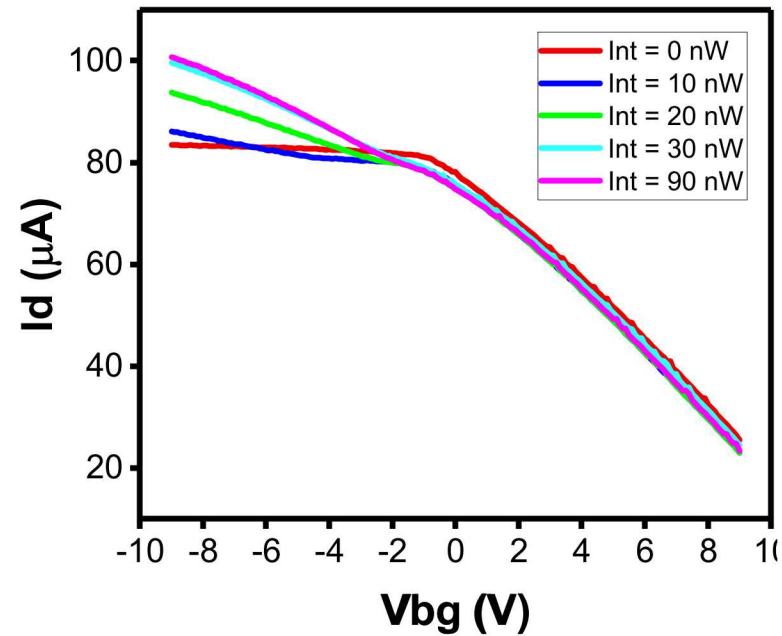


# N and P doped Graphene on n-Si and p-Si

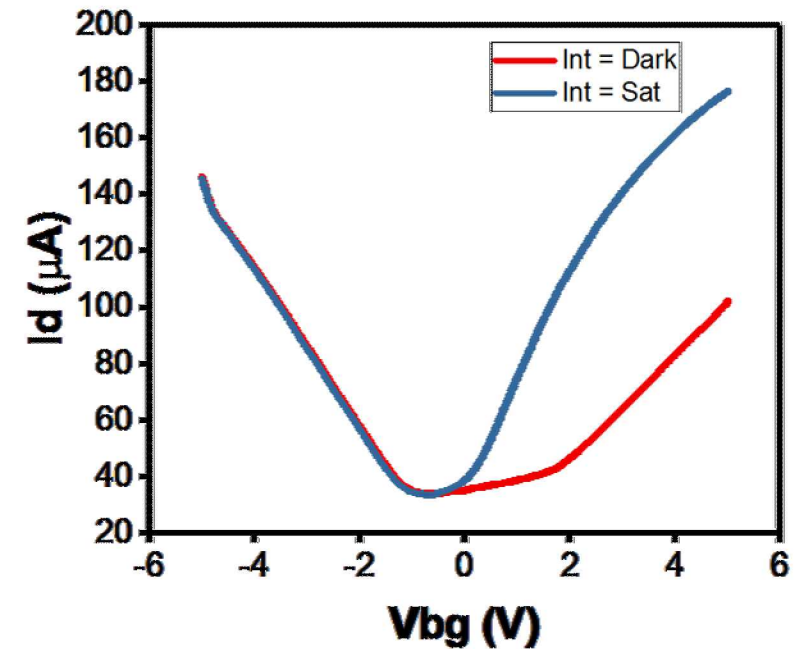
p doped Graphene on n-Si



p doped Graphene on p-Si



n doped Graphene on n-Si

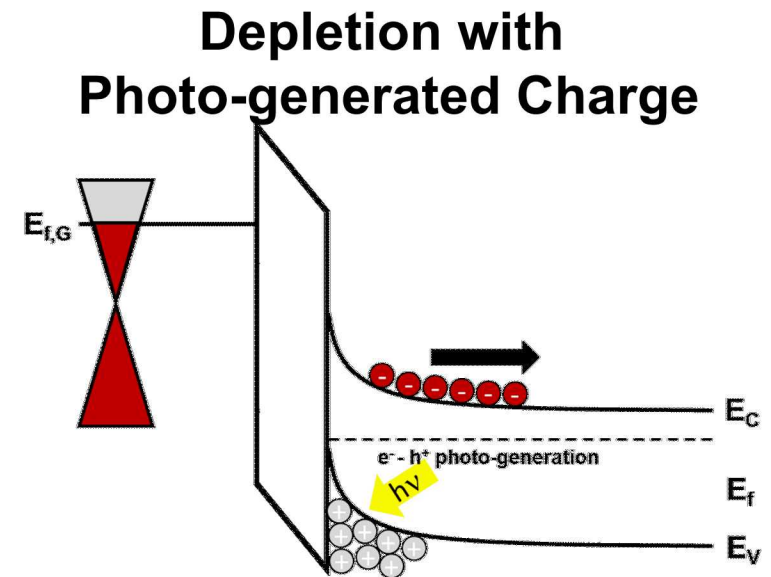
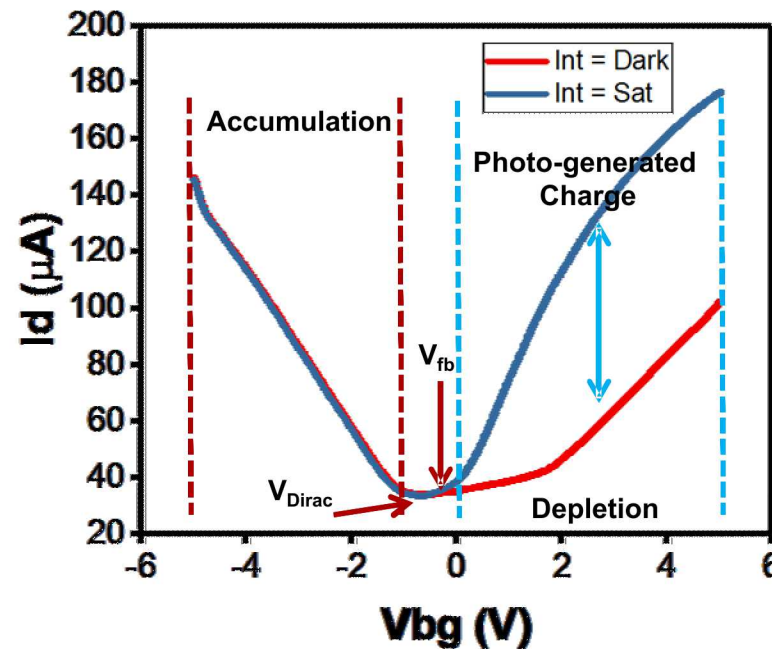
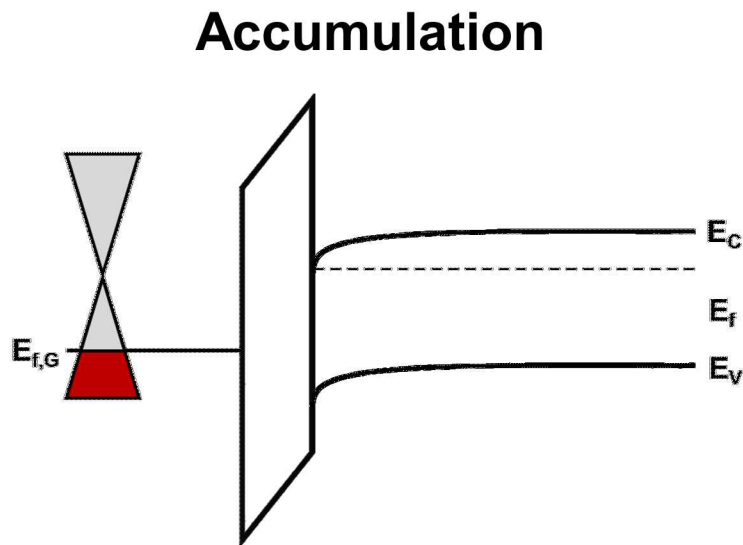
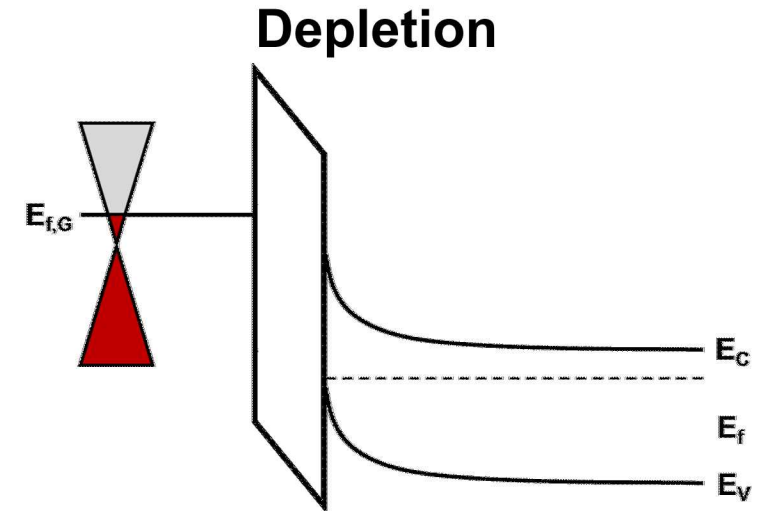
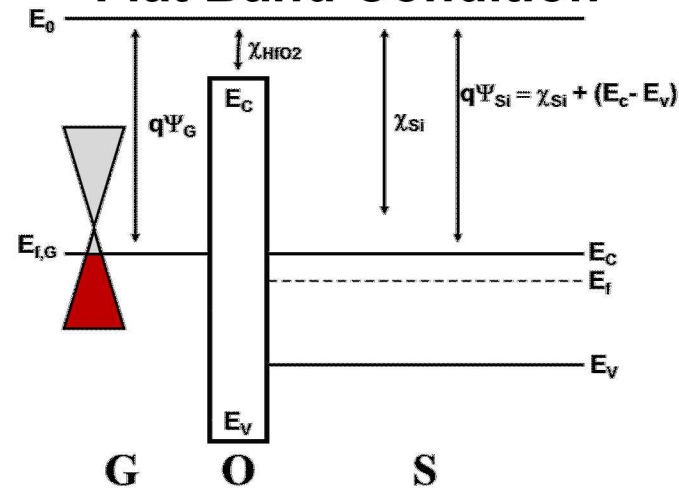
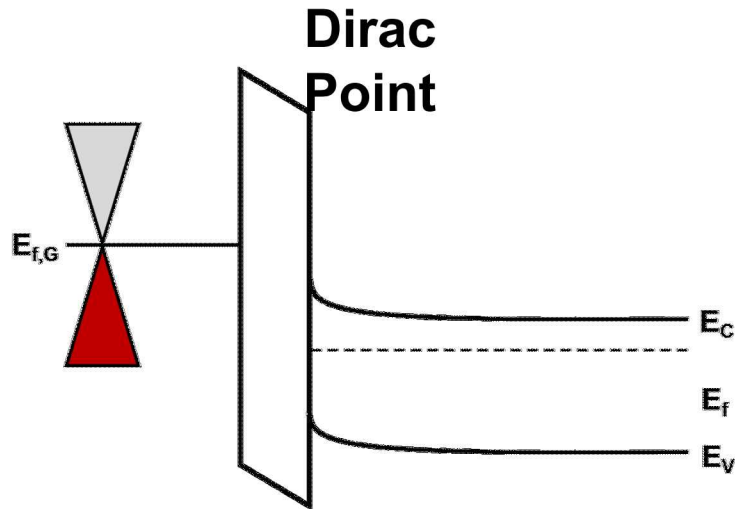


Missing Example of  
n doped Graphene on  
p--Si



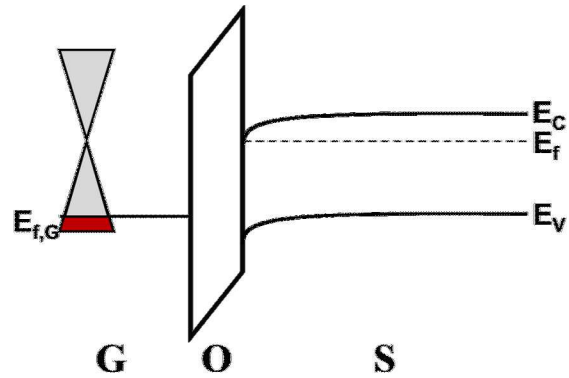
# Band Diagram of “intrinsic” graphene D<sup>2</sup>GOS Junction Detector

## Flat Band Condition



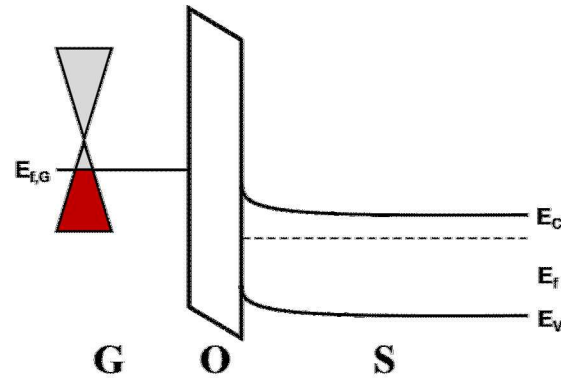
# $I_d(V_{bg}, \text{integration time})$ for p-doped graphene on n-Si

$V_{bg} < V_{fb}$   
 Accumulation



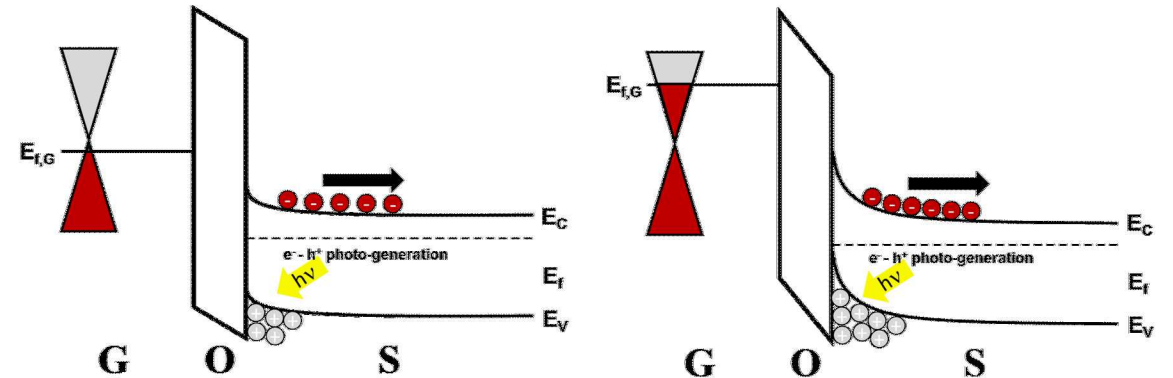
dt = 10 ms

$V_G = V_{Dirac} > V_{FB}$   
 Depletion

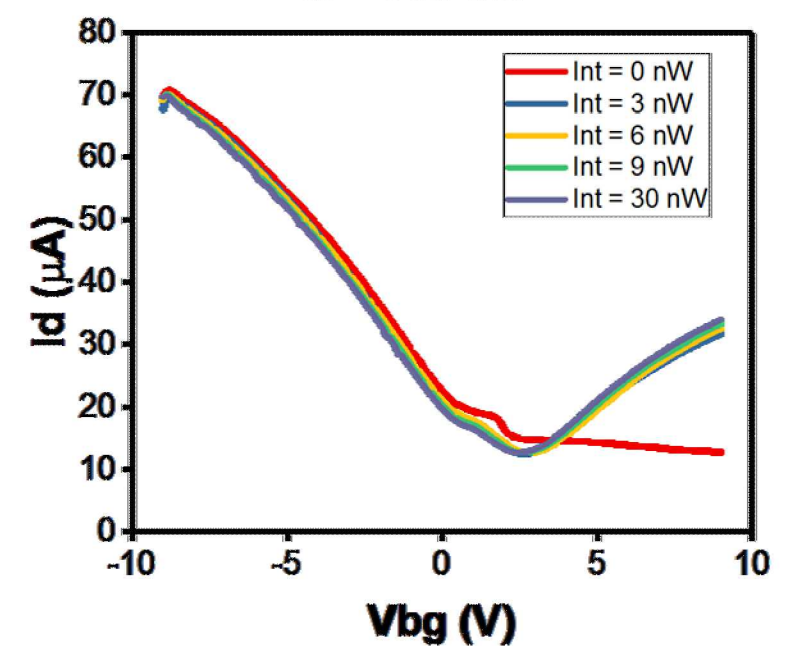
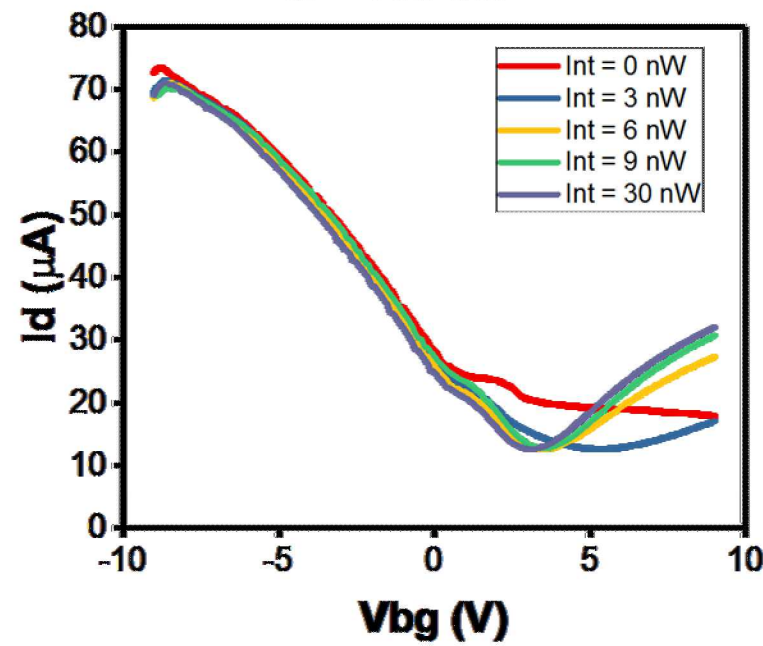
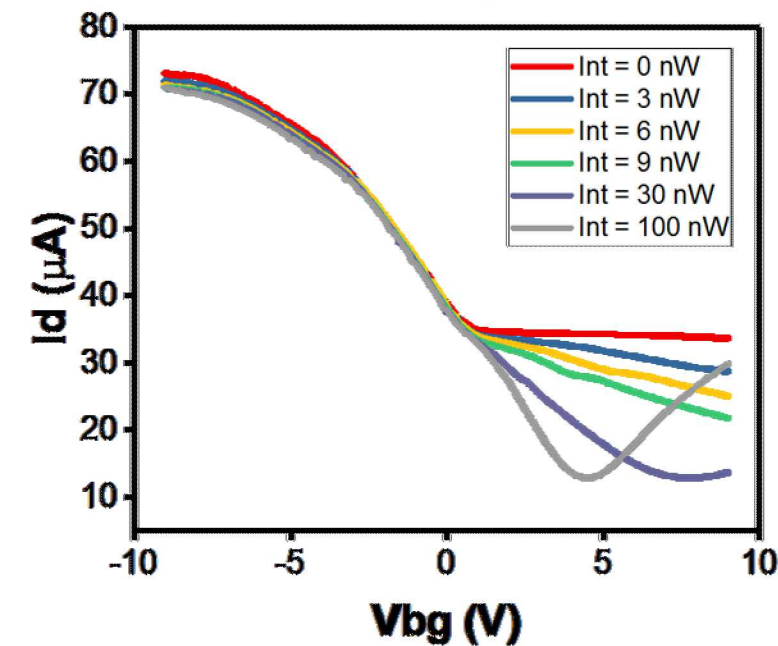


dt = 100 ms

$V_G = V_{Dirac} > V_{FB}$   
 Dep. w/Photo-gen. Charge

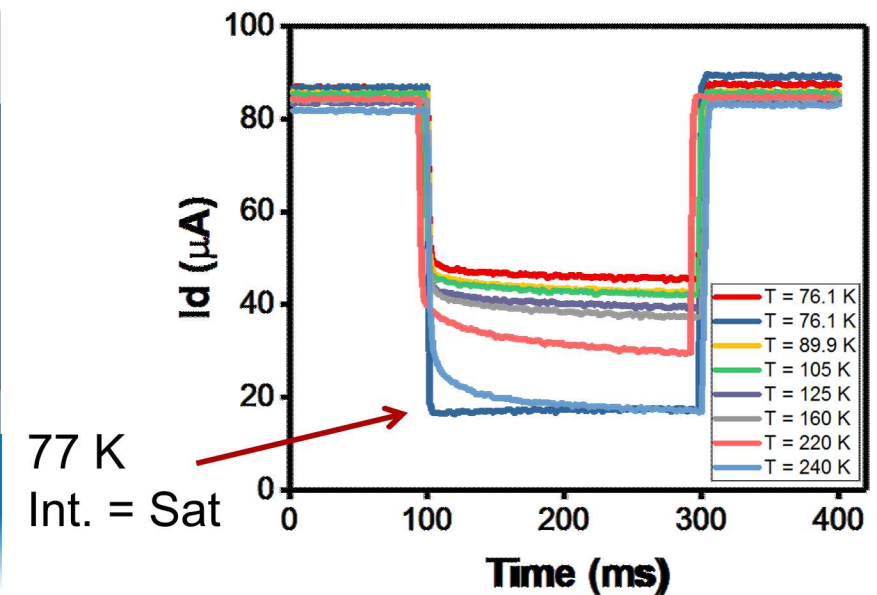
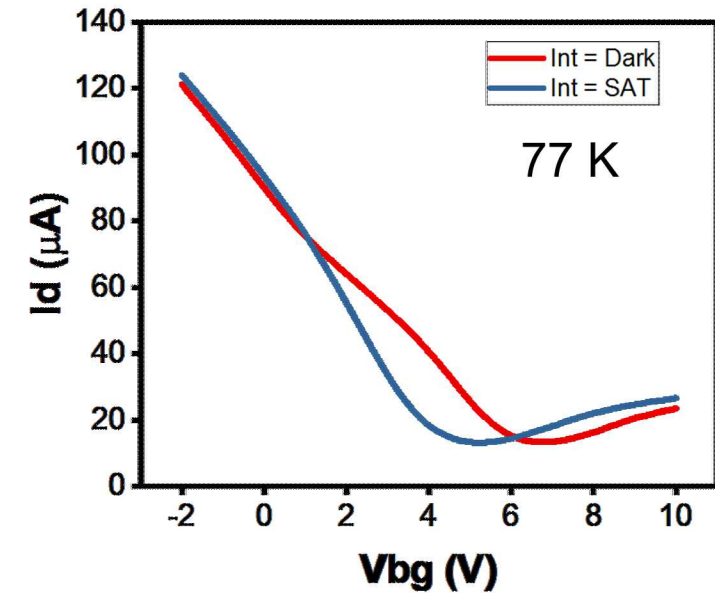
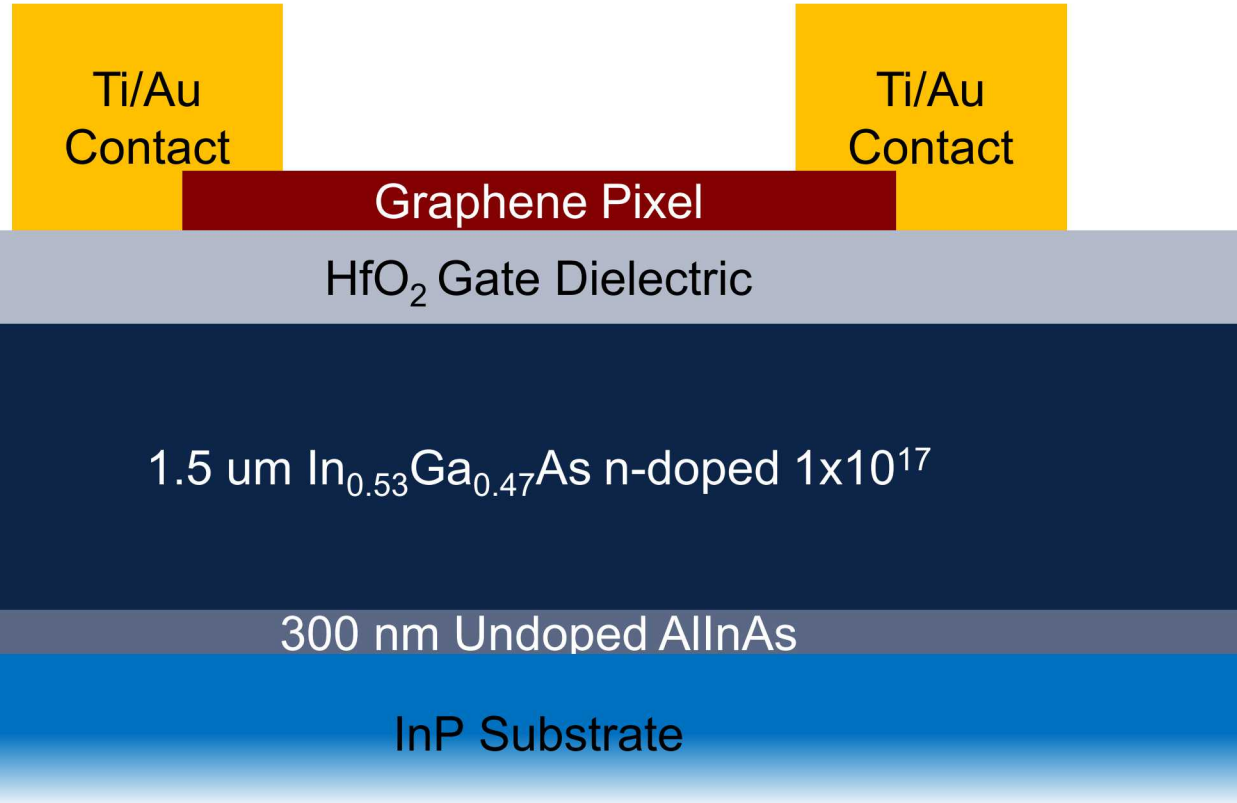


dt = 300 ms



# Demonstration of D<sup>2</sup>GOS on Shortwave IR Substrate

$E_g \sim 1.6 \text{ } \mu\text{m}$



# Conclusion

- Demonstrated a path forward for optimizing D<sup>2</sup>GOS Detectors
  - Improved Interface
  - Determining different operation modes due to graphene and substrate doping.
- Increased well lifetime to over a minute compared to 9 sec.
- Demonstrated D<sup>2</sup>GOS on III-V absorber for the first time.

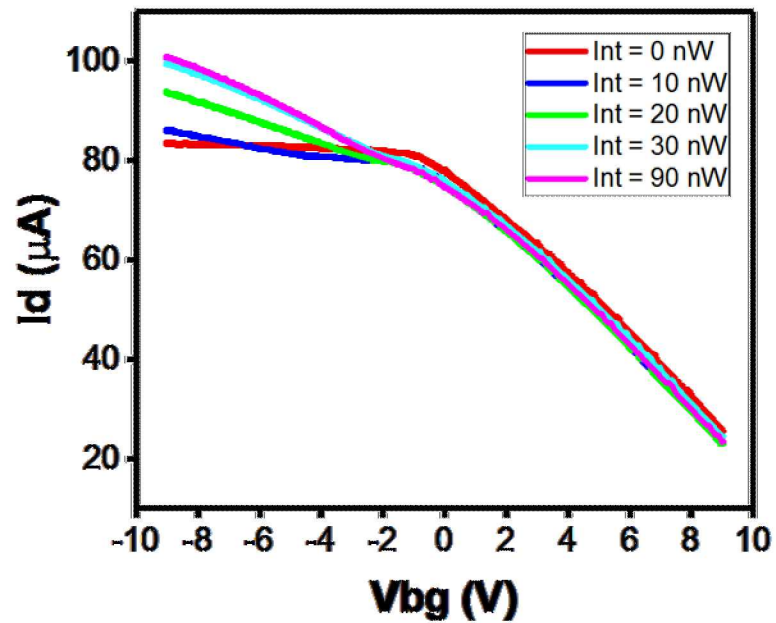


Thank You

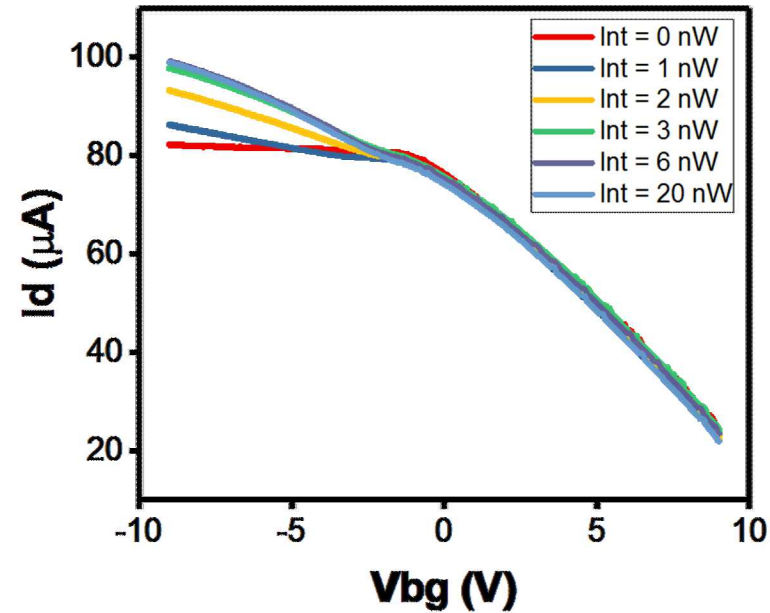
**Questions?**

# $I_d(V_{bg}, \text{integration time})$ for p-doped graphene on p-Si

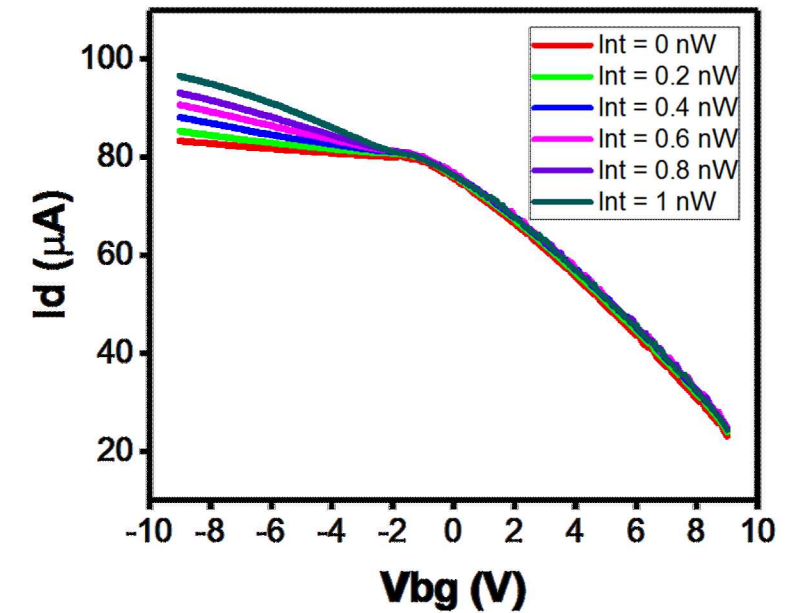
dt = 10 ms



dt = 100 ms

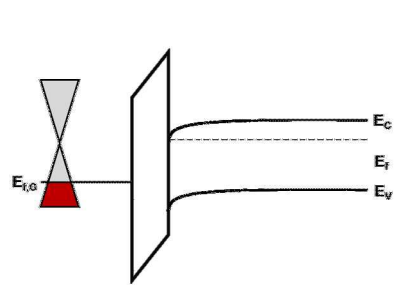


dt = 300 ms

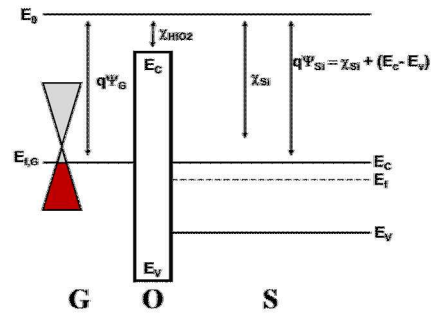


# D<sup>2</sup>GOS Band Diagram

N-Si, Intrinsic Graphene

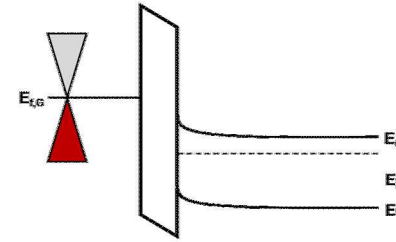


Accumulation



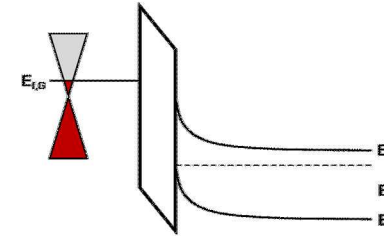
Flat Band Condition

Dirac Point

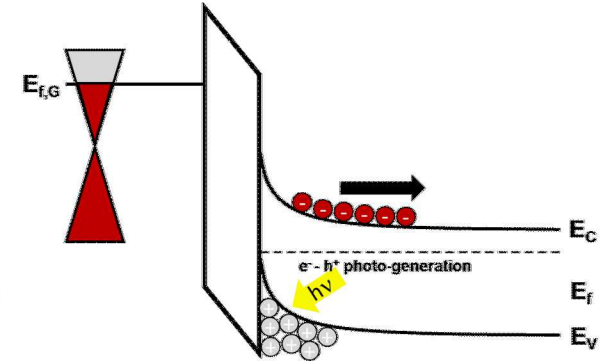


Dirac Point

Flat Band Condition



Depletion



Depletion with Photo-generated Charge

P-Si, Intrinsic Graphene

